

10000 U.S. 10  
10/07/10  
53712

PATENT NUMBER and  
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM 10071809	FILING DATE 02/07/2002	CLASS 257	SUBCLASS 689	GAU 2844	1765	EXAMINER Pen-D
<b>**APPLICANTS:</b> Wang Tinghao;						
<b>**CONTINUING DATA VERIFIED:</b> THIS APPLICATION IS A CON OF 09/342,335 06/29/1999 q/a						
<b>** FOREIGN APPLICATIONS VERIFIED:</b>						
PG-PUB <input checked="" type="checkbox"/> DO NOT PUBLISH <input type="checkbox"/> RESCIND <input type="checkbox"/>						
Foreign priority claimed 35 USC 119 conditions met Verified and Acknowledged Examiners's initials				ATTORNEY DOCKET NO 10200-16		
TITLE : Method for selectively etching silicon and/or metal silicides						

U.S. DEPT. OF COMM. / PAT. & TM-PTO-435L (Rev. 12-94)

<b>NOTICE OF ALLOWANCE MAILED</b>		<b>CLAIMS ALLOWED</b>			
		Assistant Examiner	Total Claims		
			Print Claim for O.G.		
<b>ISSUE FEE</b>		Primary Examiner	<b>DRAWING</b>		
Amount Due	Date Paid		Sheets Drwg.	Figs. Drwg.	Print Fig.
			Application Examiner		
<input type="checkbox"/> <b>TERMINAL DISCLAIMER</b>		<b>PREPARED FOR ISSUE</b>		<b>WARNING:</b> The information disclosed herein may be restricted. Unauthorized disclosure may be prohibited by the United States Code Title 35, Sections 122, 181 and 368, Possession outside the U.S. Patent & Trademark Office is restricted to authorized employees and contractors only.	

FILED WITH:

☐ CD-ROM

☐ CD-ROM

(Attached in pocket on right inside flap)